

Form PTO 1449	ATTY. DOCKET NUMBER NITT.0161	SERIAL NUMBER To Be Assigned 10/699,853 <i>cml</i>
U.S. Department of Commerce Patent and Trademark Office.	APPLICANT Shichi et al	
Information Disclosure Statement by Applicant	FILING DATE Concurrently Herewith	GROUP 2881

U.S. Patent Documents

Examiner Initial	Cited by Examiner in Parent	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE
<i>cml</i>	X	6,039,000	3/21/2000	Libby et al.			2/11/98
<i>cml</i>	X	5,270,552	12/14/93	Ohnishi et al.			8/21/92
<i>cml</i>	X	5,986,264	11/16/99	Grunewald			4/22/96
<i>cml</i>	X	5,089,774	2/18/92	Nakano			12/24/90

Foreign Patent Documents

Examiner Initial	Filed In Parent	DOCUMENT NUMBER	FILING DATE	COUNTRY	CLASS	SUB-CLASS	TRANSLATION	
							YES	NO
<i>cml</i>	X	05-052721	8/22/91	Japan			Abstract	X
<i>cml</i>	X	WO99/05506	7/21/98	WO			Abstract	X
<i>cml</i>	X	03-166744	11/27/89	Japan			Abstract	X

Other Documents (Including Author, Title, Date Pertinent Pages, Etc.)

Filed in Parent		
<i>cml</i>	X	L.A. Giannuzzi, J.I. Drown, S.R. Brown, R. B. Irwin, F.A. Stevie, "Focused Ion Beam Milling and Micromanipulation Lift-out for Site Specific Cross-Section TEM Specimen Preparation", Material Research Society Symposium Proceeding (1997), Vol, 480, pp. 19-27.
<i>cml</i>	X	L.R. Herlinger, S. Chevacharoenkul, D.C. Erwin, "TEM Sample Preparation Using a Focused Ion Beam and a Probe Manipulator", Proceedings of the 22 nd International Symposium for Testing and Failure Analysis, 18-22 November 1996, pp. 199-205
<i>cml</i>	X	"Election and Ion Beam Handbook", Third Edition, (Japan Society for the Promotion of Science, 132 commission, Nikkan Kogyo ShinbunSha), pp. 458-461

EXAMINER <i>Chris Lalor</i>	DATE CONSIDERED 04/23/04
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